Amendments to the Claims

This listing of claims will replace all prior versions, and listings, of claims in the application.

Listing of Claims:

1. (Currently Amended) A method of growing a gallium nitride single crystal using a flux comprising at least sodium metal, said method comprising:

growing said gallium nitride single crystal in an atmosphere comprising gas mixture comprising nitrogen gas under and having a total pressure of 300 atms to 1200 atms and at a temperature of 850°C to 1200°C, said atmosphere having a nitrogen partial pressure of 120 atms to 600 atms.

- 2. (Currently Amended) The method of claim 8, wherein said atmosphere has a nitrogen partial pressure of 100 atms to 2000 atms.
- 3. (Previously Presented) The method of claim 8, wherein said crystal is grown at a temperature of 900°C to 1500°C.
- 4. (Previously Presented) The method of claim 1, wherein said crystal is grown at a temperature of 950°C to 1200°C.
- 5. (Previously Presented) The method of claim 1, further comprising the step of elevating a crucible containing said flux until a seed crystal contacts said flux.
- 6. (Previously Presented) The method of claim 1, wherein said gallium nitride single crystal is grown using a system for hot isostatic pressing.
- 7. (Cancelled).

8. (Currently Amended) A method of growing a gallium nitride single crystal using a crucible containing a flux comprising at least sodium metal, with a moving part attached to a lower portion of the crucible and a seed crystal fixed over the crucible, said method comprising:

elevating the crucible by the moving part until the seed crystal contacts said flux;

growing said gallium nitride single crystal in an atmosphere comprising a gas mixture comprising nitrogen gas under and having a total pressure of 300 atms to 2000 atms; and

driving the crucible downward by the moving part to separate the seed crystal from said flux.

- 9. (Previously Presented) The method of claim 8, wherein said crystal is grown at a temperature of 950°C to 1200°C.
- 10. (Previously Presented) The method of claim 8, wherein said gallium nitride single crystal is grown using a system for hot isostatic pressing.
- 11. (New) The method of claim 1, wherein the gallium nitride single crystal is grown at a rate of at least 25 μ m/hr.
- 12. (New) The method of claim 8, wherein the gallium nitride single crystal is grown at a rate of at least 25 μ m/hr.